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ALL  
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Case No. 10269/3

In re Application of:

**CONVEYANCE SYSTEM**

Serial No: 09/490,507

Examiner: Steven A. Bartlie

Filed: January 25, 2000

Group Art Unit: 3652

For: Takumi MIZOKAWA, Makoto  
MORI, Yuzo TAKAKADO, Hitoshi  
KAWANO

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JUN 14 2002

**GROUP 3600**

Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

Before the examination of the present application, please enter the following amendment and consider the following remarks:

**IN THE CLAIMS:**

(1) Please replace claim 1 with the following new claim 1 (APPENDIX 1):

*Dub 01/*  
*1*

1. (twice amended) A wafer conveyance system, comprising:  
a chamber having a plurality of outgoing ducts from its circumference, each  
connecting to an insertion portion of each one of a plurality of wafer processing apparatuses;  
a guide path provided in said chamber;  
a mobile element movable along said guide path, and capable of receiving one or  
more processed wafers, via said duct, from said insertion portion of one of said wafer